

# Giant Magneto-Impedance Effect in Multilayer Thin Film Sensors

---

SEAN HEINZE

ADVISORS: AHMED ALFADHEL, DR. SANTOSH KURINEC, DR. LYNN FULLER

ROCHESTER INSTITUTE OF TECHNOLOGY, DEPARTMENT OF ELECTRICAL AND  
MICROELECTRONIC ENGINEERING, ROCHESTER NY 14623

# Overview

---

Introduction

Theory of Operation

Design

Process

Process Challenges

Testing

Applications

Conclusion

# Introduction

Magnetic sensors output a voltage or resistance due to an external magnetic field

Magnetic sensors currently in industry:

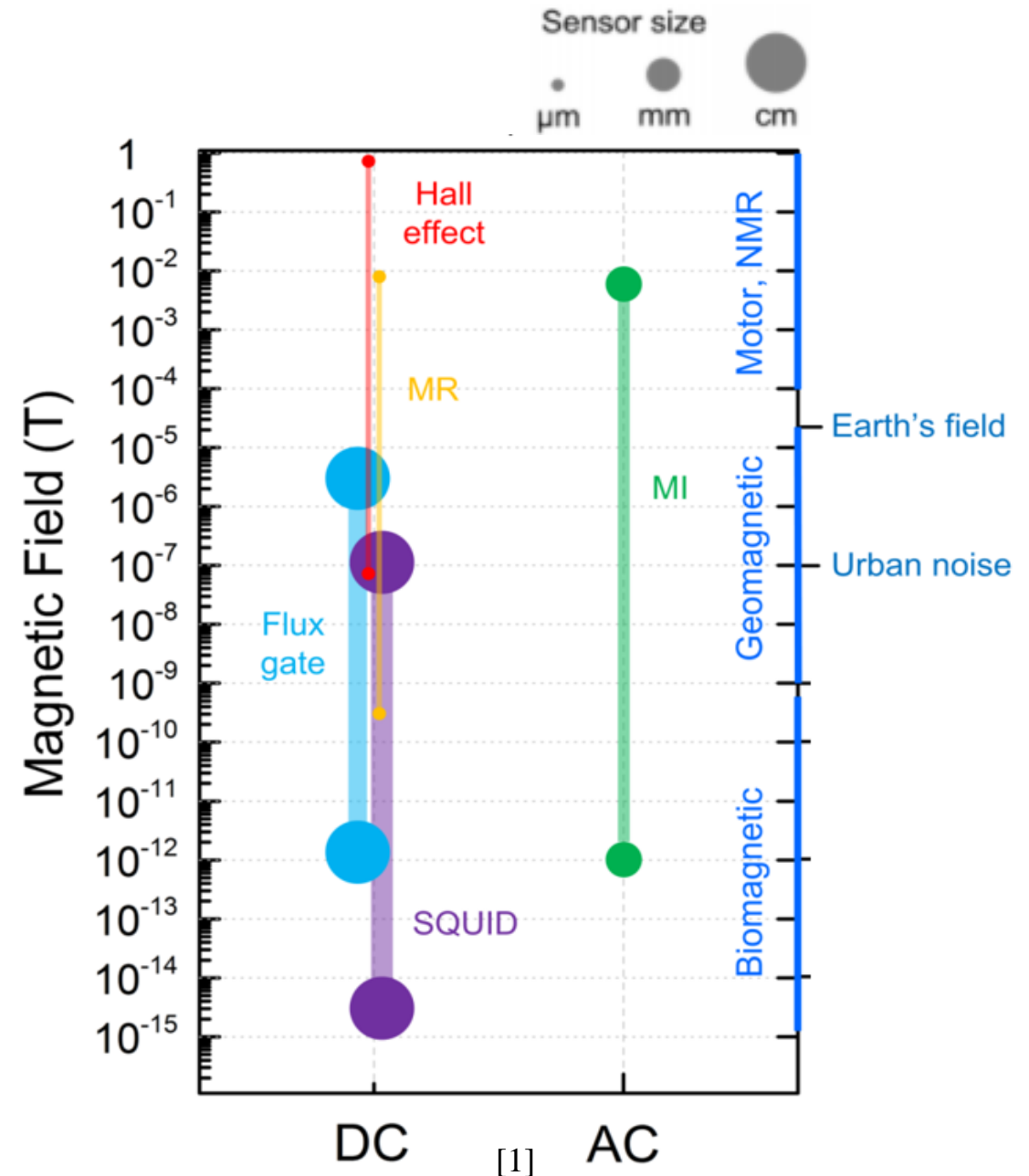
- Flux-gate
- Hall-effect
- Giant-Magneto Resistance (GMR),
- superconducting quantum interference device (SQUID)

GMI sensor:

- Offers high sensitivity, small size, large operating range, low production costs

Fabricated multilayer thin film GMI sensors

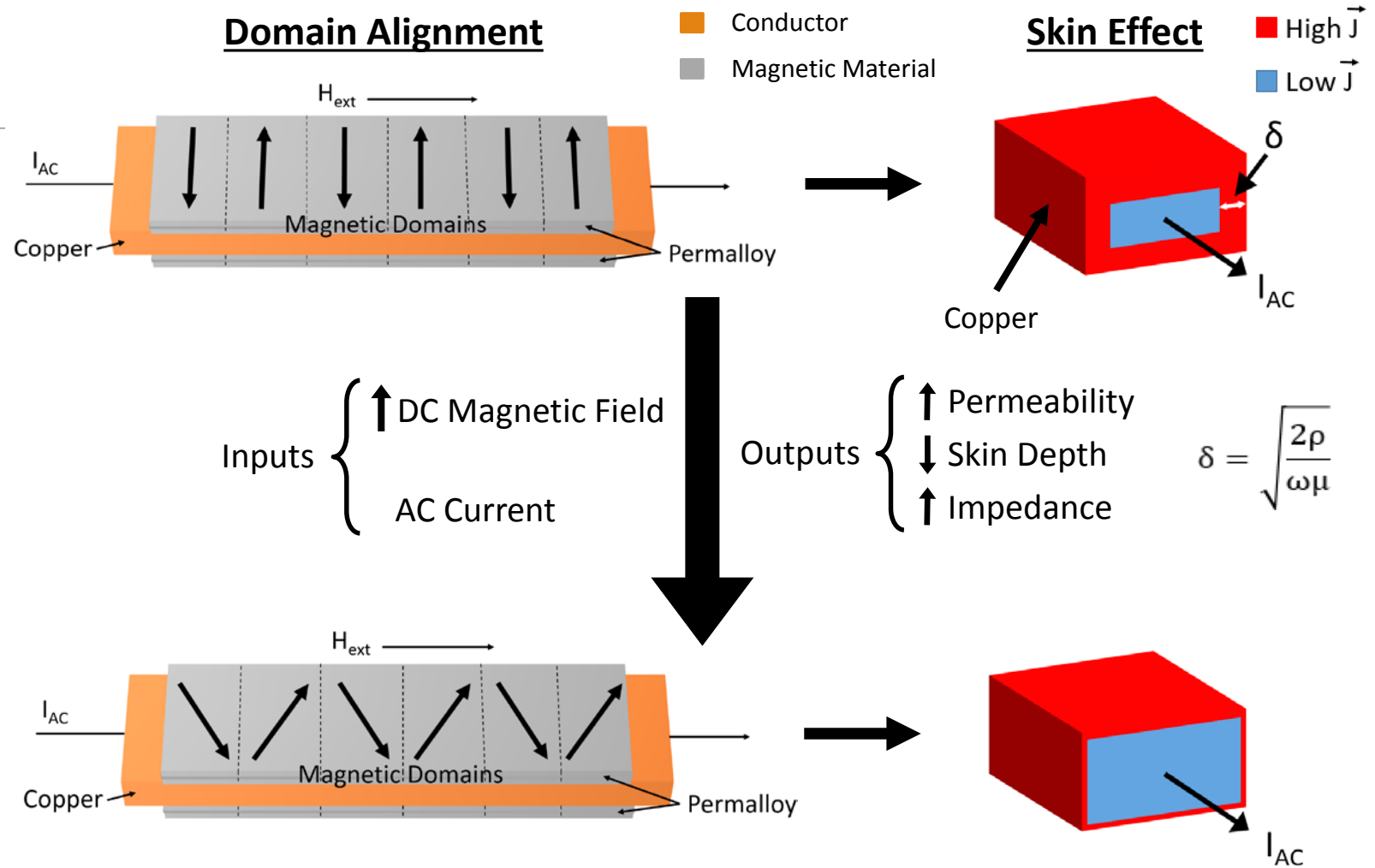
- Conductive layer, Cu, sandwiched between two soft ferromagnetic films, Permalloy (Ni 80%, Fe 20%)
- Measures change in magnetic field and outputs impedance



# Theory of Operation

## How does it work?

- GMI Effect:** Change in complex impedance of the magnetic material while under bias by an external DC magnetic field,  $H_{ext}$ 
  - $H_{ext}$  causes magnetic domain wall rotation in the magnetic material of the sensor
  - Shifting of the domains changes magnetic permeability,  $\mu$
  - Increase in permeability results in decrease in skin depth,  $\delta$
  - Decreasing skin depth results in increasing impedance,  $Z$



# Theory of Operation

---

**Impedance and Skin Depth Equations:**

$$\delta = \sqrt{\frac{2\rho}{\omega\mu}} \quad k = \frac{i+1}{\delta} \quad Z = R_{DC} * \frac{kt}{2} \coth\left(\frac{kt}{2}\right)$$

**Performance Criteria:**

$$\text{GMI Ratio} = \frac{\Delta Z}{|Z_0|} = \frac{(Z_{H_{\text{ext}}=H} - Z_{H_{\text{ext}}=0})}{Z_{H_{\text{ext}}=0}} \quad \% \text{ Sensitivity} = \frac{d\left(\frac{\Delta Z}{Z_0}\right)}{dH_{\text{ext}}} * 100$$

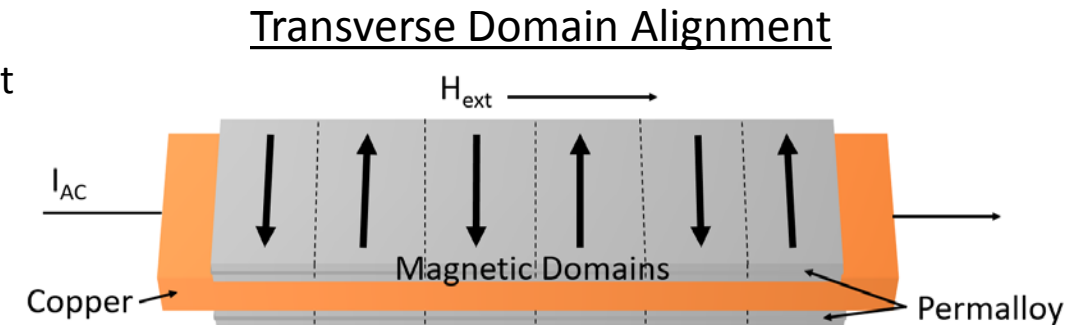
# Design

## Materials:

- Permalloy – soft ferromagnetic material with high remnant magnetization and low coercivity
- Copper – low resistivity

## Geometric Design Goals:

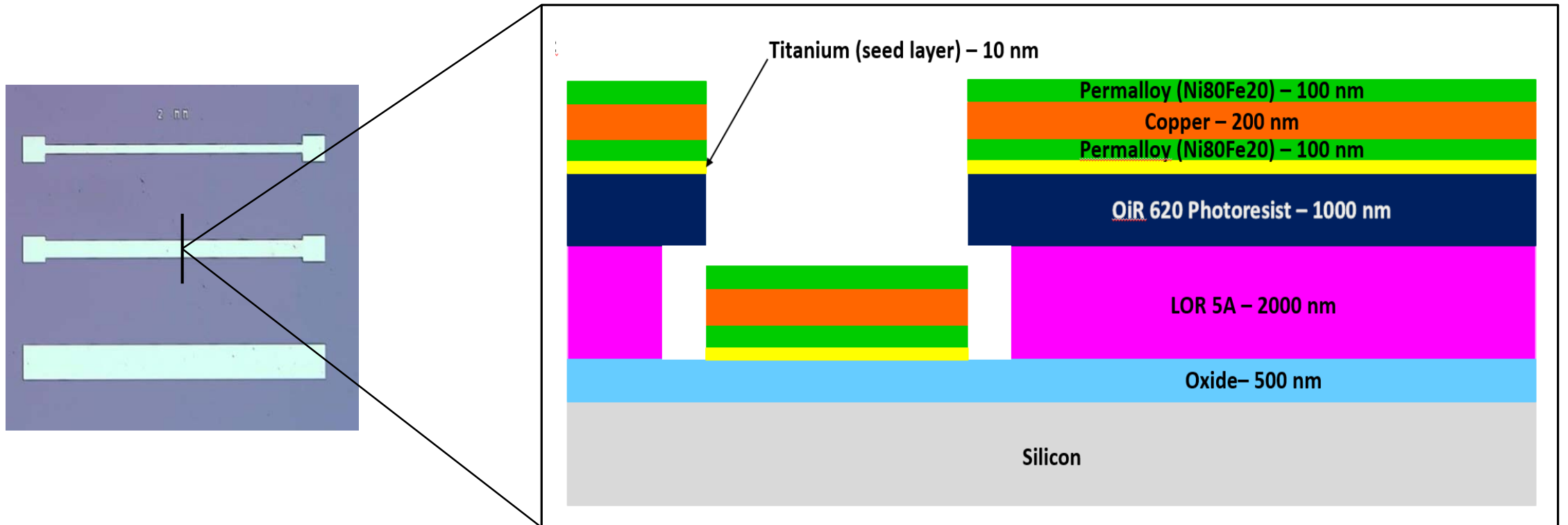
- To Induce **transverse anisotropy** (perpendicular magnetic domain alignment to the easy axis, direction of current)
  - More perpendicular alignment → performance increases
- Domains tend to randomly align in lowest energy state
  - Can be overcome through design and processing
- **Experimentation:** Varying width, length, and Permalloy thickness
- Target dimensions for max transverse domain alignment
  - Best performance seen at higher frequencies (300 – 500 MHz)
- Multilayer stack can be integrated into standard CMOS processes
- Multiple magnetic films increase overall inductive reactance



Film Thickness (Py / Cu/ Py) [nm]	Width [um]	Length [mm]
50 / 200 / 50	50	1
100 / 200 / 100	100	2
200 / 200 / 200	200	4

# Design Theory – Film Stack

Cross-section

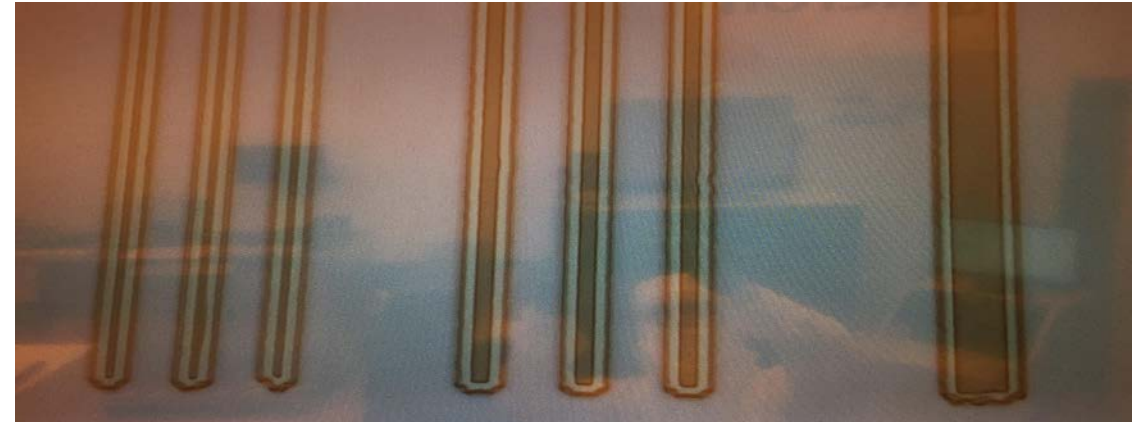


# Process – Lift-off

---

## Bi-Layer Lift-off:

- Coat LOR 5A: (~1.0 – 1.1 um thickness)
  - Spin speed: 1000 rpm
  - Softbake 150 C for 60 sec (or 60 sec/1 um layer (if multilayered))
- Coat OiR620: (~1.0 um thickness)
  - NOHMDS.RCP recipe on SII track
  - Spin speed: 3400 rpm (5 sec) and 2000 rpm (25 sec)
  - Softbake: 93 C for 60 sec
- Exposure: Karl Suss MA 150 – 250 mJ, ~60 sec
- PEB: 112 C for 60 sec
- Develop: Puddle 90 sec
- No hardbake (can destroy undercut profiles)

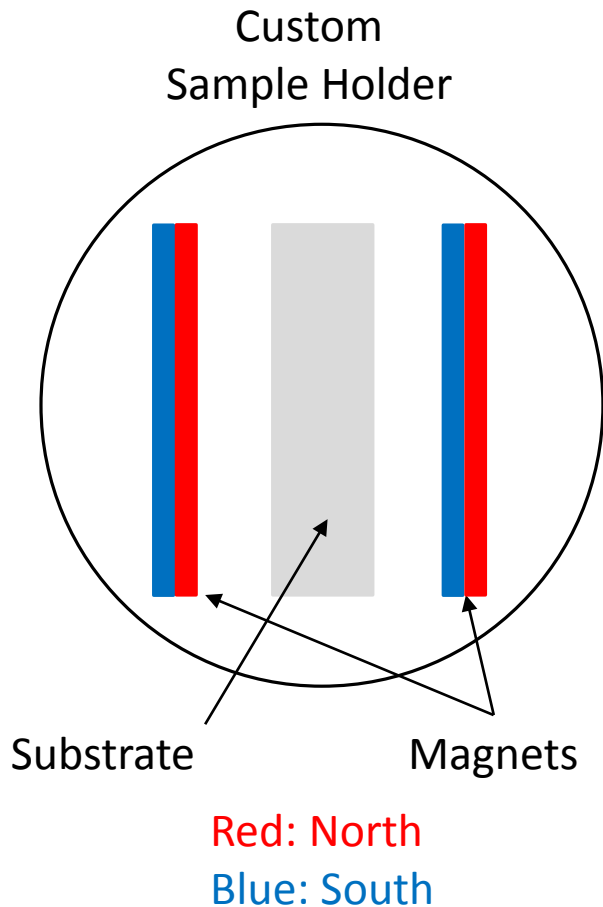


**3 um undercut  
→ Reduced develop  
time to 90 sec to  
achieve 1 um  
undercut**

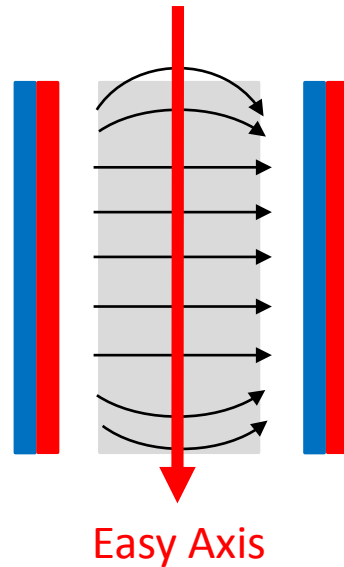
**SEM: Lift-off Profile**



# Process - Deposition



Magnetic Field Uniformity



Deposition via e-beam evaporation in presence of magnetic field

- Overcomes shape anisotropy
- Induce transverse anisotropy

Constructed custom substrate holder

- Two magnets: neodymium
- 2.5 in. spacing generates 45 mT of magnetic field @ center
- Accommodates 2 in. wide and 4 in. long substrates
- Magnet Spacing adjustable to change field strength

# Process Modifications

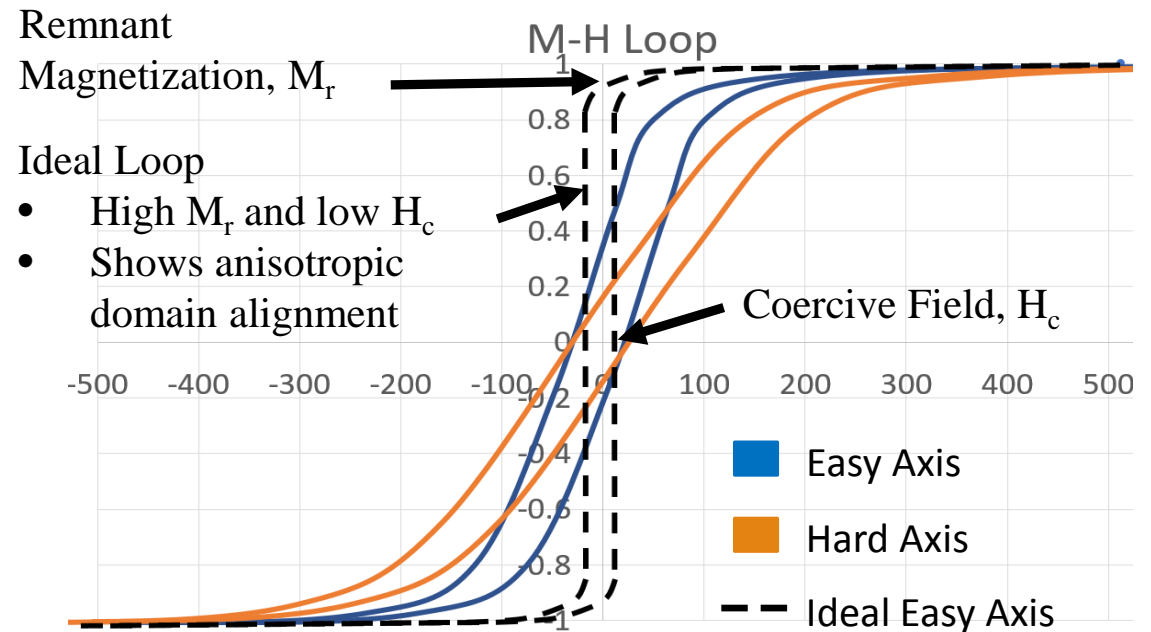
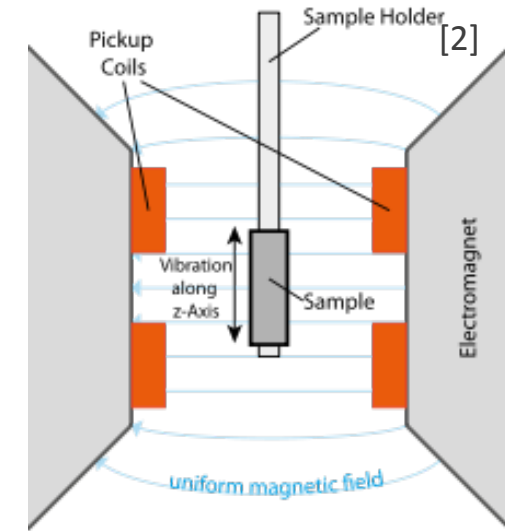
- Permalloy exhibited stress and adhesion issues
  - Added Titanium layer to reduce film stress
  - Descum and hardbake added for adhesion issues
- Ti layer changes film resistivity difference
  - Reduction in performance

Run #	Hardbake 60 sec @ 140C	Descum 30 sec	2x LOR Thickness	Ti Seed Layer	Magnet Spacing	Process as Piece	Comments
1	0	0	0	0	0	0	Permalloy & resist peeled off
2	X	0	0	0	0	0	"
3	0	X	X	X	0	0	Less visible peeling
4	X	X	X	X	0	0	"
5	0	0	X	X	0	0	"
6	X	0	X	X	0	0	"
7	0	0	X	X	X	0	"
8	0	0	X	X	X	X	Significant improvement for peeling, able to salvage some devices

# Testing Part 1

## Domain Alignment Testing

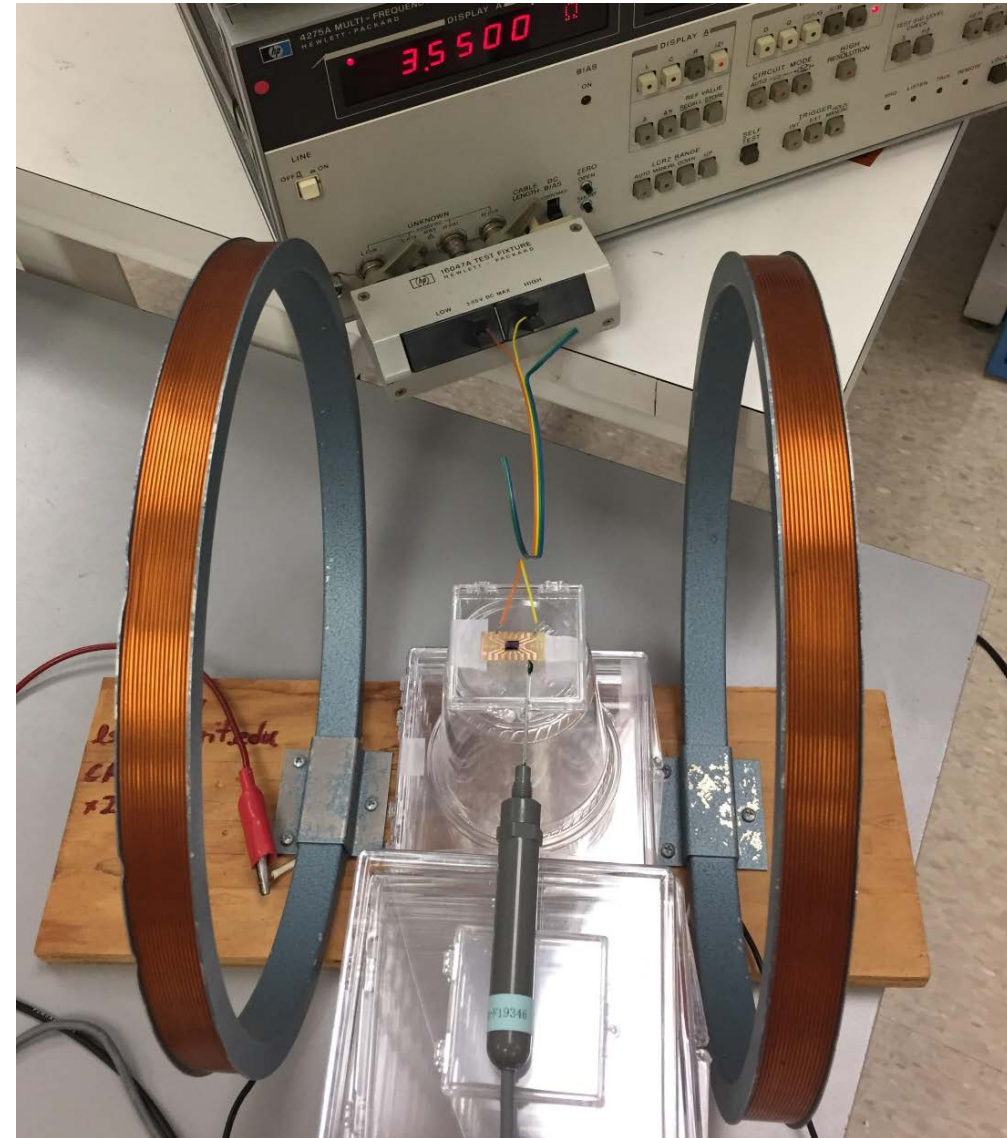
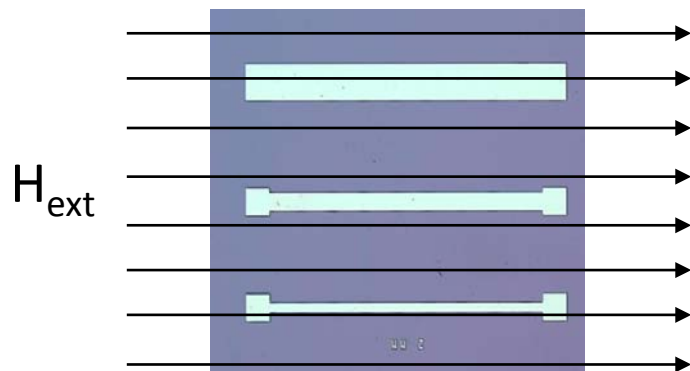
- Tested using a Vibrating Sample Magnetometer
- Vibration generates an electromotive force (EMF)
- EMF picked up by sense coils
- Signal conditioned by amplifier to readout magnetic moment vs. field (hysteresis loop)



# Testing Part 2

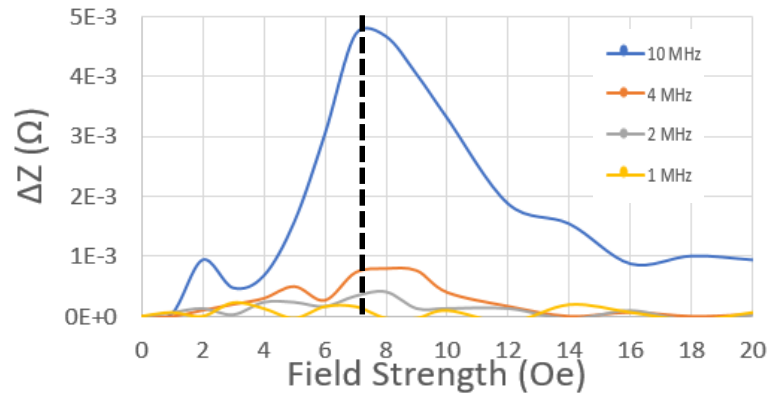
## Impedance Test Setup

- Applied uniform magnetic field using Helmholtz coil set
- Mounted sample in the center of the coils
- Wirebond GMI sensor onto PCB
- Sweep field 0 – 20 Oe, measured Z at multiple frequencies

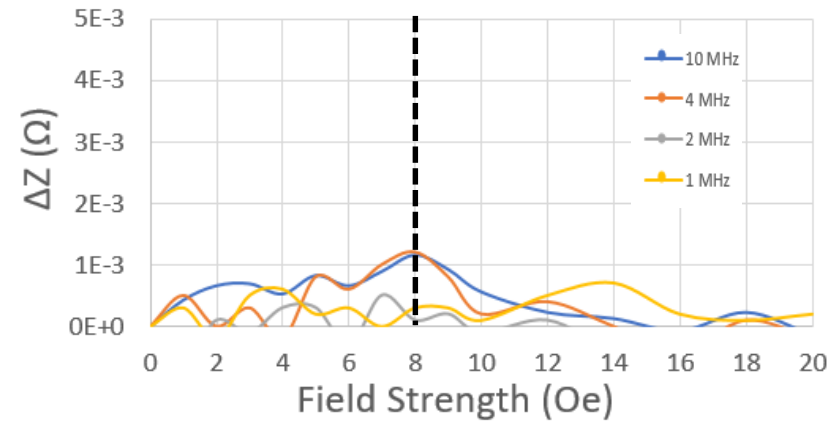


# Testing Part 2

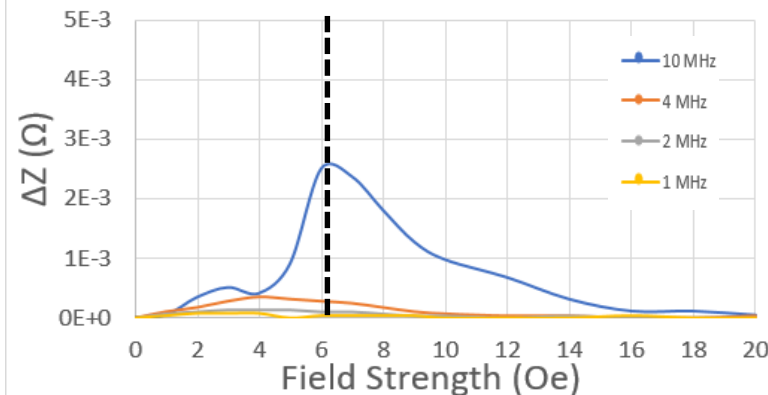
100 um Width,  $\Delta Z$  vs. Field Strength



50 um Width,  $\Delta Z$  vs. Field Strength



200 um Width,  $\Delta Z$  vs. Field Strength



- Measured only 2 mm sensors due to process issues
- Sensors made for higher frequencies of 300 -500 MHz
- 100 um feature width @ 10 MHz exhibits best  $\Delta Z$  response
- Max  $\Delta Z$  between 6 – 8 Oe
  - Ferromagnetic resonance occurs in this range for 10 MHz
  - Here  $\delta$  is significantly smaller than conductor thickness
- 50 and 200 um features showed smaller  $\Delta Z$ 
  - Due to difficulty overcoming shape anisotropy

# Testing Part 2

---

2 mm Sensor Performance				
	Experimental @ 10 MHz		Calculated @ 500 MHz	
Width	GMI Ratio	Sensitivity	GMI Ratio	Sensitivity
50 um	0.015 %	0.009 %/Oe	-	-
100 um	0.028 %	0.01 %/Oe	1.43 %	0.5 %/Oe
200 um	0.007%	0.002 %/Oe	-	-

# Applications

---

- **Electronic Compasses** – Low power and size reduction solution to currently used flux-gate sensors for geomagnetic field sensing. Highly used in boats/the motor industry. <sup>[4]</sup>
- **High-Density Magnetic Memory** – Reading module in magnetic storage drives. Reads localized remnant magnetization bits from write operation. Currently lower sensitivity GMR sensors used for magnetic memory. <sup>[4]</sup>
- **Magnetic Immunoassay** – Detection of pathogens and other biomolecules with magnetic bead labels in blood samples. <sup>[4]</sup>
- **Automated Highway System** – Research in Japan proposes automated driving using a magnetic guidance system, which employs a GMI sensor to sense magnetic markers fixed in the road. <sup>[4]</sup>

# Conclusion

---

- Processing Permalloy was proven very difficult and resulted in loss of test structures for experimental design
- Successfully fabricated GMI sensors of 2 mm length and varying width
- Best performance seen in 100  $\mu\text{m}$  wide sensor
- Failed to meet performance expectations
- Performance lower than expected due to insufficient domain alignment and inclusion of Titanium layer

## **Future Work**

- Determine functional process without Titanium seed layer → Significantly improve performance
- Perform DOE on sensor geometries to find optimum performance criteria
- Study the effect of inter-dielectric material between conductor and magnetic layers, which is hypothesized to produce better performance @ lower frequencies



# References

---

- [1] L. Kraus, "Theory of giant magneto-impedance in the planar conductor with uniaxial magnetic anisotropy." J. of magnetism and magnetic materials, 195(3): 764-778, 1999.
- [2] "Vibrating Sample Magnetometer," Wikipedia. <https://en.wikipedia>
- [3] Borge, Amruta, "Giant Magneto-impedance Effect In Thin Film Layered Structures," University of Central Florida STARS, 2005. [Online].
- [4] M.H. Phan, H.X. Peng, "Giant Magnetoimpedance Materials: Fundamentals and Applications," Progress in Materials Science, Science Direct. [Online].
- [5] L.V. Panina, K. Mohri, "Magneto-impedance in multilayer films," Sensors and Actuators A: Physical, 01-Apr-2000. [Online].
- [6] P. B. Jayathilaka, C. A. Bauer, D. V. Williams, Casey W. Miller, "Influence of Growth Field on NiFe, Fe<sub>3</sub>O<sub>4</sub>, and NiFe/Cr/Fe<sub>3</sub>O<sub>4</sub> Spin-Valves," IEEE Transactions on Magnetics, 6-Jun-2010. [Online].

Thank You